



## ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18  
Stylesheet Version v18.0

Title of  
Invention

SOLVENT FREE PHOTORESIST STRIP AND RESIDUE  
REMOVAL PROCESSING FOR POST ETCHING OF LOW-  
K FILMS

Application Number: 10/761122



Confirmation Number: 8790

First Named Applicant: HUONG NGUYEN

Attorney Docket Number: AMAT5735C1

Search string: ('6214728 or 6130166 or 6124213 or 6074569  
or 6062237 or 6046115 or 6043004 or 6037255  
or 6030901 or 6024045 or 5811358 or 5681780  
or 5660682 or 4357203 or 4028155 ).pn.

### US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
<input checked="" type="checkbox"/>	1	6214728	2001-04-10	CHAN, ET AL.			
<input type="checkbox"/>	2	6130166	2001-10-10	YEH			
<input type="checkbox"/>	3	6124213	2000-09-26	USAMI, ET AL.			
<input type="checkbox"/>	4	6074569	2000-06-13	KIZILOGLU, ET AL.			
<input type="checkbox"/>	5	6062237	2000-05-16	BROWN, ET AL.			
<input type="checkbox"/>	6	6046115	2000-04-04	MOLLOY, ET AL.			
<input type="checkbox"/>	7	6043004	2000-03-28	KURIMOTO			
<input type="checkbox"/>	8	6037255	2000-03-14	HUSSEIN, ET AL.			
<input type="checkbox"/>	9	6030901	2000-02-29	HOPPER, ET AL.			
<input type="checkbox"/>	10	6024045	2000-02-15	KIKUCHI, ET AL.			
<input type="checkbox"/>	11	5811358	1998-09-22	TSENG, ET AL.			
<input type="checkbox"/>	12	5681780	1997-10-28	MIHARA, ET AL.			
<input type="checkbox"/>	13	5660682	1997-08-27	ZHAO, ET AL.			
<input checked="" type="checkbox"/>	14	4357203	1982-11-02	ZELEZ			
<input checked="" type="checkbox"/>	15	4028155	1977-06-07	JACOB			

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R. Duda

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Comments